

#1203

<b>LIST OF REFERENCES CITED BY APPLICANT</b> <i>(Use several sheets if necessary)</i>					ATTY. DOCKET NO.:		APPLICATION NO.:	
					4717-5300		10/728743	
					APPLICANT:			
					Christophe MALEVILLE et al.			
					FILING DATE:		GROUP:	
					12/3/01		2026	
<b>U.S. PATENT DOCUMENTS</b>								
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
EP	AA	5,994,207	11/1999	Henley et al.	438	515		
EP	AB	6,265,314 B1	7/2001	Black et al.	438	690		
EP	AC	6,284,628 B1	9/2001	Kuwahara et al.	438	459		
EP	AD	6,596,610 B1	7/2003	Kuwahara et al.	438	458		
EP	AE	2001/0055854 A1	12/2001	Nishida et al.	438	455		
<b>FOREIGN PATENT DOCUMENTS</b>								
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
EP	AF	EP 0 955 671 A1	11/1999	Europe			X	
EP	AG	EP 1 156 531A1	11/2001	Europe			X	
EP	AH	EP 1 170 801 A1	1/2002	Europe			X	
EP	AI	WO 98/52216	11/1998	PCT			X	
EP	AJ	WO 01/80308 A2	10/2001	PCT			X	
<b>OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)</b>								
EP	AK	XP000326239, "SURFACE PROFILOMETER WITH ULTRA-HIGH RESOLUTION" IBM Technical Disclosure Bulletin, IBM Corp, Vol. 35. No. 3, pp. 207-208 (1992)						
EP	AL	M. Bruel, Auberton-Herve et al., "INDUSTRIAL STATUS OF SOI WAFER PRODUCTION AND NEW MATERIAL DEVELOPMENTS", Smart Technology, ECS Spring Meeting 99, Electronics Division, 9th Int'l Symposium on Silicon on Insulator Technology.						
	AM							
EXAMINER					DATE CONSIDERED			
Evan Pert					4-27-05			
<b>*EXAMINER:</b> Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								



#0404

<b>LIST OF REFERENCES CITED BY APPLICANT</b> (Use several sheets if necessary)				ATTY. DOCKET NO.:		APPLICATION NO.:	
				4717-5300		10/728,343	
				APPLICANT:			
				Christophe MALEVILLE et al.			
				FILING DATE:		GROUP:	
				December 3, 2003		2812-2826	
<b>U.S. PATENT DOCUMENTS</b>							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
EP	AA	6,426,270 B1	7/2002	Sakaguchi et al.	438	406	
	AB						
	AC						
	AD						
	AE						
<b>FOREIGN PATENT DOCUMENTS</b>							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
EP	AF	FR 2 794 891 with English Abstract	12/2000	France			X
EP	AG	JP 11297583 with English Abstract	1/1980	Japan			X
	AH						
	AI						
	AJ						
<b>OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)</b>							
EP	AK	K. Mitani, " Technical Challenges in High Volume Unibond SOI Wafer Manufacturing", Semicon West 98, SOI Seminar (1998)					
	AL						
	AM						
<b>EXAMINER</b> Evan Pert				<b>DATE CONSIDERED</b> 4-27-05			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							